

**In the Claims:**

Following is a complete listing of the claims pending in the application, as amended:

Please cancel claims 1-7 and add new claims 8-16.

8. (New) An apparatus for processing workpieces, comprising:  
a device support having a first alignment surface;  
a processing vessel carried by the device support at a carrying plane, the processing vessel being configured to receive at least one processing liquid;  
a workpiece support positioned to carry the workpiece at least proximate to the processing vessel;  
a drive unit operatively coupled to the workpiece support to move the workpiece support relative to the processing vessel; and  
a mounting portion coupled to the workpiece support and having a second alignment surface removably mated with the first alignment surface, with the workpiece support being supported relative to the device support only at or above the carrying plane.
9. (New) The apparatus of claim 18 wherein the mounting portion includes a base.
10. (New) The apparatus of claim 18 wherein the drive unit is operatively coupled to the workpiece support to rotate the workpiece support about a rotation axis.
11. (New) The tool of claim 18 wherein the processing vessel is configured to receive an electrochemical processing liquid.

12. (New) The apparatus of claim 18 wherein the processing vessel extends below the carrying plane.

13. (New) The apparatus of claim 18 wherein the workpiece support is configured to carry the workpiece in contact with a processing liquid.

14. (New) The apparatus of claim 18 wherein the workpiece support includes at least one contact assembly having at least one electrical contact positioned to make contact with the workpiece.

15. (New) The apparatus of claim 18 wherein the workpiece support includes at least one electrode and at least one sheath positioned to seal against a surface of the workpiece.

16. (New) The apparatus of claim 18 wherein the carrying plane includes an aperture in which the processing vessel is received.